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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Docket No. 2001-0660A  
Norio KIMURA et al. : **Confirmation No. 1632**  
Serial No. 09/864,208 : Group Art Unit 1763  
Filed May 25, 2001 : Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS  
AND SUBSTRATE POLISHING METHOD

**SUBMISSION OF FORMAL DRAWINGS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Enclosed is 1 sheet of formal (A-4) drawing (Fig. 4) submitted herewith.

Respectfully submitted,

Norio KIMURA et al.

By:

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October 6, 2003

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